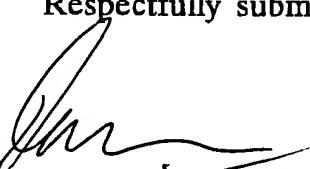
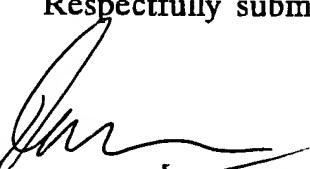


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1 Inventor: V. Segal; S. Ferrasse; F. Alford

2 Title: Physical Vapor Deposition Targets, and Methods of Fabricating Metallic
3 Materials4 Assignee: Honeywell International Inc. *H2*5 **INFORMATION DISCLOSURE STATEMENT** *C.7*6 **PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98** *2/18/01*7 In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, the Examiner's
8 attention is directed to the references listed on the attached Form PTO-1449
9 and copies of which are attached. No admission is made regarding whether
10 all the submitted references are prior art.

11 Citation of this patent these references is respectfully requested.

12 13 Date: 11/01/0014 Inventor: Vladimir Segal
V.M. Segal15 Date: 11/02/0016 Inventor: S. Ferrasse
S. Ferrasse17 Date: 11/02/0018 Inventor: F. Alford
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